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Automated defect classification system

YH Brezner, BL Paul, PYH Hsieh, DM Parker, R, ... - US Patent, 1996 - Google Patents
 ... describe a **wafer defect** detection and classification system in "An Automated **Wafer** Inspection System ... **based** classifier that does not provide for uncertainty in the **defect** measures ... literature on using concepts of fuzziness as an uncertainty measure in classification applications ...
[Cited by 53](#) - [Related articles](#)

Automatic defect classification for semiconductor manufacturing

PB Chou, AR Reo, MC Stautzenberger, FY Wu, ... - Machine Vision and ..., 1997 - Springer
 ... Patterned **wafer** inspection tools can optically detect **defects** less than 0.5 micron in diameter. ... Much of the excitement of ADC arises from the challenge of the classification technology ... be constructed by representing their knowledge in terms of rules that relate **defect** attributes to ...
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Model-based clustering for integrated circuit yield enhancement

JY Hwang, W Kuo - European Journal of Operational Research, 2007 - Elsevier
 ... The curvilinear feature is one of the typical patterns observed on **wafer defect** maps with ... Approximate modeling of curvilinear **defect** patterns with the bivariate normal distribution may ... information about the characteristics of clusters and decrease the classification capability [14]. ...
[Cited by 11](#) - [Related articles](#) - [All 7 versions](#)

Monitoring wafer map data from integrated circuit fabrication processes for spatially clustered defects

MH Hansen, VN Nair, DJ Friedman - Technometrics, 1997 - JSTOR
 ... In general, clusters of **defects** can be classified as either particle or process related, with particle-related clusters being attributable to individual machines and process-related clusters being ... MONITORING WAFER MAP DATA FOR SPATIALLY CLUSTERED DEFECTS ...
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[PDF] Recent progress in industrial machine vision

O Morimoto, JLC Sanga - International Journal of Robotics and Automation, 1993 - mva.org.jp
 patches. The likelihood of the presence of the match of a feature point in the other image should be high. It ... circled region. To obtain statistical information on the **wafer**, a **defect** classification circuit can be used. This circuit ...
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mva.org.jp [PDF]

[PDF] Determining composition of grain mixtures by texture classification based on feature distributions

T Ogata, M Fukukawa, J Naito - International Journal of Pattern ..., 1998 - Elsevier
 ... The proposed applications include, for example, the detection and identification of surface **defects** on metal surfaces, textiles or semiconductor **wafers**, the assessment of ... This procedure was repeated for all samples and the classification error rate was determined as the ...
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pau.edu [PDF]

A cost-based heuristic for statistically determining sampling frequency in a wafer fab

GF Chant, SC Hsu, S Peng, CH Wu - 2000 - 140 114 72-23
 ... However, 100% inspection is practiced at **wafer** sort to **classify** dice, we assume that there is ... as well as the optimal allocation of inspection capacity depends on the **defect** variability ... needed for extending the proposed method to deal with the whole in-line **wafer** sampling strategy ...
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A model-based clustering approach to the recognition of the spatial defect patterns produced during semiconductor fabrication

F Yuan, W Kuo - IEEE Transactions, 2006 - informaworld.com
 ... The indexing values for classification, the ν_i in the classification likelihood function (2), satisfy $\nu_i \neq \nu_j$ if $k_i \neq k_j$. In the parameter estimation ... in the simulation studies, the diameter of the **wafers** is 20 cm. ... The intensity function used in the global **defect** generation is quadratic, that is ...
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A hybrid fuzzy-statistical clustering approach for estimating the time of changes in fixed and variable sampling control charts

A Alneidmi, M Ghazvini, MA Naveiri - Information Sciences, 2009 - Elsevier
 ... and more rational than expert control charts which are used in monitoring **wafer defects** during IC ... (4) use expert technology to select unstable slicing machines to control **wafer** slicing quality ... (2) Similar to clustering methods, change-point models are used to **classify** patterns; almost ...
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Spatial defect pattern recognition on semiconductor wafers using model-based clustering and Bayesian inference

F Yuan, W Kuo - European Journal of Operational Research, 2009 - Elsevier
 ... Section 2 describes the mixture model used to describe the **defect distributions** on the **wafers**. ... In both approaches, the locations s_i are regarded as incomplete data and the complete data are considered to be (s_i, z_i) , where the classification variables $z_i = (z_{i0}, z_{i1}, \dots, z_{iG})$...
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